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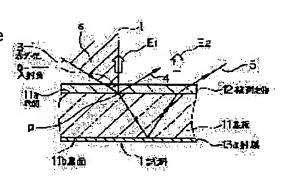
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## (54) METHOD FOR MEASURING INFRARED REFLECTION SPECTRUM AND ITS SAMPLE (57) Abstract:

PURPOSE: To provide a method for measuring infrared reflection spectrum which can detect an extremely thin film formed on the surface of a substrate for semitransmitting infrared light and its sample.

CONSTITUTION: A rear surface 11b of a sample 1 where an object 12 to be measured in thin-film state is formed on a surface 11a of a substrate 11 for transmitting infrared light is polished to mirror-surface state. Then, a reflection film 13 for reflecting infrared light is stuck to the rear surface 11b which is polished to mirror surface. Then, infrared light 3 which is subjected to P polarization is applied to the sample 1 from the side of the object 12 to be measured. Then, the spectra of the infrared rays 4 and 5 which are reflected from the sample 1 are measured. Also, the surface 11a of the substrate 11 is in mirror—surface state.



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